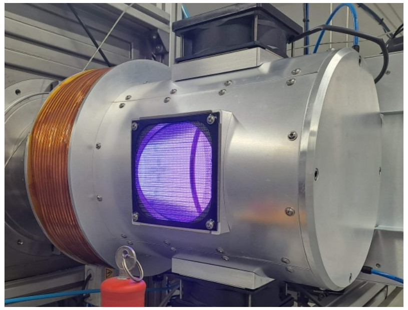
Plasma Quest Ltd

Thin film sputter systems with:-

- Plasma Quest's HiTUS® Technology
- Highly uniform and reproducible multi-layer deposition
- Independent control of plasma power and sputter target power
- Fully automated PC control
- Switchable RF or DC target bias
- Co-Sputtering option available
- Substrate heating or cooling
- Substrate bias (etch/conformal coverage)
- Loadlock integration option
- Excellent material properties
- Additional process parameters
- Superb reactive deposition control
- High coating adhesion
- OES, remote IR, QMS, TFTM

Large area systems
(batch and R to R)



PQL HiTUS® Plasma source,
available as a retrofit

Custom Designed PVD Coating Systems with HiTUS®

Versatile deposition systems to deposit High Quality Thin Films

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